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Accession number & update

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TitleEffect of rapid thermal annealing treatment on electrical properties and microstructure of **tantalum oxide** thin film deposited by plasma-enhanced chemical vapor deposition.**Author(s)**

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Publication type

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Treatment codes

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Abstract

Effect of high temperature annealing in the temperature range of 600-900 degrees C on the electrical properties and microstructure of **tantalum pentoxide** (Ta₂O₅) thin film deposited by plasma-enhanced chemical vapor deposition (PECVD) was studied. Leakage characteristics of the Ta₂O₅ thin film annealed at 600 degrees C were found to be the best in this study. However, it was observed that the leakage current in the polycrystalline Ta₂O₅ thin film decreased with increasing the annealing temperature above 800 degrees C after a peak for 700 degrees C annealing. The dielectric constant of the annealed Ta₂O₅ thin film was 26 after annealing at 600 degrees C, and decreased with the same tendency as the leakage current characteristics. Transmission electron microscopy (TEM) and X-ray diffraction (XRD) analysis indicated that the microstructure of the Ta₂O₅ thin film annealed above 800 degrees C was of delta-Ta₂O₅ with hexagonal **crystal structure**. Furthermore, TEM and AES observations

revealed that Ta-O-Si transition-layers were formed between the annealed Ta/sub 2/O/sub 5/ thin film and Si substrate. The electrical properties of the Ta/sub 2 /O/sub 5/ films are discussed in terms of interface modification and film densification due to rapid thermal annealing treatment. (16 refs) .

Descriptors

Auger-effect; crystal-microstructure; densification; electrical-conductivity; insulating-thin-films; leakage-currents; permittivity; plasma-CVD-coatings; rapid-thermal-annealing; tantalum-compounds; transmission-electron-microscopy; VLSI; X-ray-diffraction.

Keywords

rapid thermal annealing; electrical properties; microstructure; Ta₂O₅ thin film; plasma enhanced chemical vapor deposition; ULSI circuits; leakage current; dielectric constant; TEM; X ray diffraction; Auger electron spectra; interface modification; film densification; 600 to 900 C; Ta₂O₅.

Classification codes

A6170A (Annealing processes).
A6855 (Thin film growth, **structure**, and epitaxy).
A7360H (Electronic properties of insulating thin films).
A6480G (Microstructure).
A7720 (Dielectric permittivity).
A7740 (Dielectric loss and relaxation).
A7920F (Electron-surface impact: Auger emission).
A8280P (Electron spectroscopy for chemical analysis (photoelectron, Auger spectroscopy, etc.)).

Chemical indexing

Ta₂O₅ bin, Ta₂ bin, O₅ bin, Ta bin, O bin.

Numerical indexing

temperature: 8.73E+02 to 1.17E+03 K.

Copyright statement

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